## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE AS DESIGNATED/ELECTED OFFICE

Applicant: Philippe Cormont, et al.	)	Title: Method and Device for Lithography by
	)	Extreme Ultraviolet Radiation
Serial No.: To be assigned	)	
	)	Group Art Unit: To be assigned
Intl. Appl. No.: PCT/FR2004/002226	)	
	)	Examiner: To be assigned
Intl Filing Date: 01 September 2004	)	•
	)	Filed: Herewith

## PRELIMINARY AMENDMENT ACCOMPANYING FILING OF NATIONAL STAGE APPLICATION UNDER 35 U.S.C. 371

Mail Stop PCT Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Sir:

Prior to examination, please amend the accompanying application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 11 of this paper.